

Docket No.: 4539-0116PUS1  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:  
Ken NAKANISHI

Application No.: 10/588,164

Confirmation No.: 4109

Filed: August 1, 2006

Art Unit: 2826

For: ION DOPING APPARATUS, ION DOPING  
METHOD, SEMICONDUCTOR DEVICE AND  
METHOD OF FABRICATING  
SEMICONDUCTOR DEVICE

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Examiner: E. T. Pert

**REPLY TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the Restriction Requirement dated October 19, 2009, the following remarks are respectfully submitted in connection with the above-identified application.

This reply includes: REMARKS.